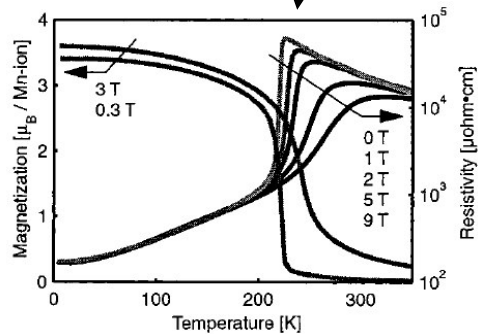


Spatial Electronic Phase Separation in Manganites

Coupled metal-insulator/ferromagnetic-paramagnetic transition

Bulk Crystal
 $\text{La}_{0.7}\text{Ca}_{0.3}\text{MnO}_3$

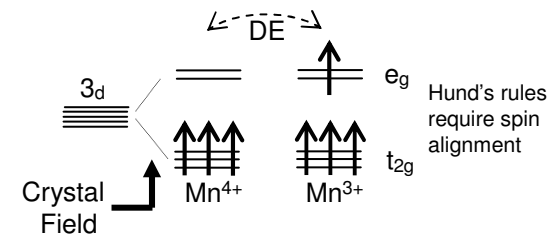


Zero field R-T curve

- below $T_c \rightarrow$ metallic ($dp/dT > 0$) \rightarrow “scattering” as $T \uparrow$
- above $T_c \rightarrow$ insulating ($dp/dT < 0$) \rightarrow thermally activated

Below T_c

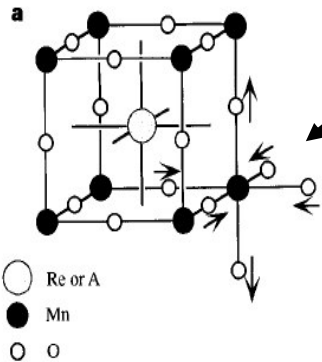
- spins aligned \rightarrow ferromagnetic \leftrightarrow double exchange
- mixed valence via doping



- conduction via hopping

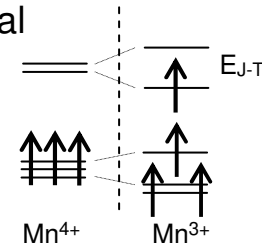
Above T_c

- spin disorder \rightarrow paramagnetic \rightarrow electron scattering
- dominated by polarons (electron-phonon coupling)



Jahn-Teller Distortion

- \rightarrow electron on Mn distorts O-Mn octahedral
- \rightarrow potential minimum
- \rightarrow self-trapped electrons



spatial electronic phase separation

- \rightarrow coexisting but spatially distinct insulating & metallic domains
- \rightarrow broadens R-T peak

Colossal magneto resistance (CMR)

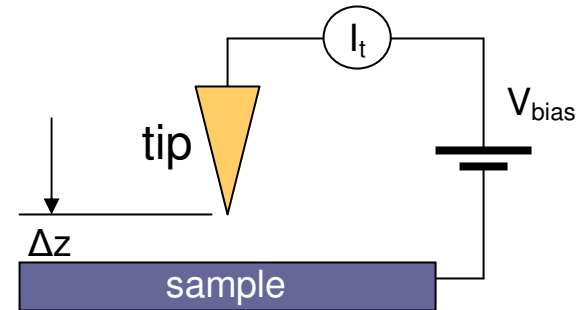
applied magnetic field \rightarrow align spins \rightarrow decrease PM (insulating) & increase FM (metallic) $\rightarrow R \downarrow$

Scanning Tunneling Spectroscopy (STS)

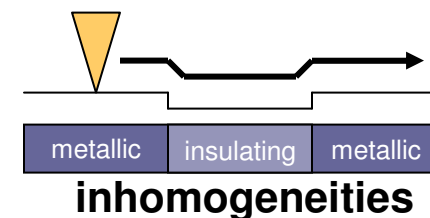
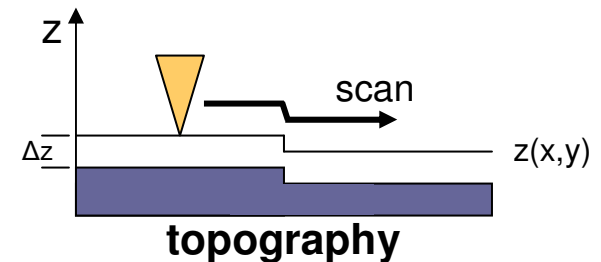
- tunneling current given by,

$$I_t(\Delta z) = I_0(v_{\text{bias}}, \text{DOS}) e^{-2\kappa\Delta z}$$

- Δz tip-surface distance
- V_{bias} tip-surface potential difference
- DOS tip & sample density of states
- κ proportional to surface work function



- STM topography
 - fix V_{bias} maintain $I_{\text{set}} = I_t$
 - adjust tip height, z , while scanning across surface
 - electronically homogeneous sample, $z(x,y)$ values map topography
 - inhomogeneous sample, changes in DOS modify I_0
 - insulating material may require minimum V_{bias}

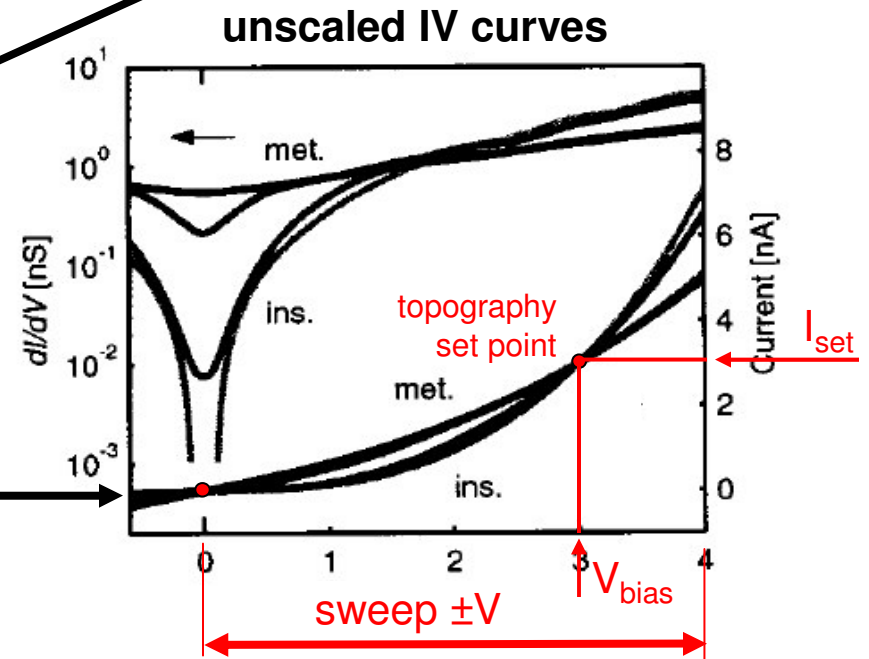
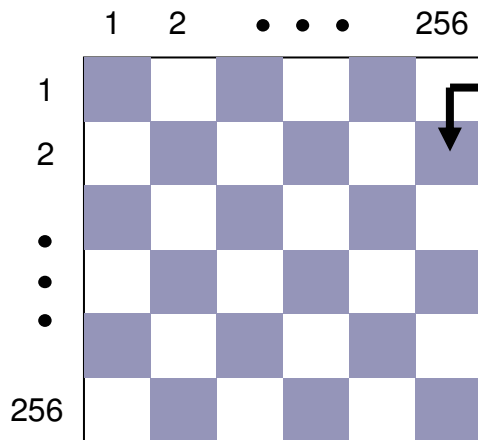


Scanning Tunneling Spectroscopy

- STS → measure sample DOS

$$I_t(\Delta z) = I_0(V_{\text{bias}}, \text{DOS}) e^{-2\kappa\Delta z}$$

- scan topography
- at each pixel take I-V
 - stop scanning → x, y fixed
 - feedback off → Δz fixed
 - sweep bias $\pm V$
 - measure I_t
 - differentiate I-V curve for dI/dV



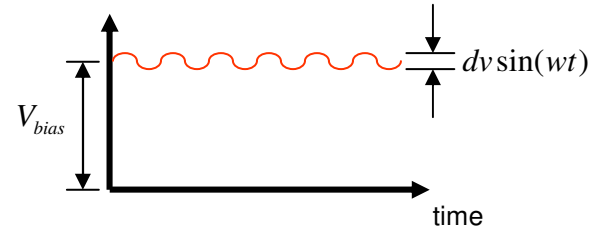
- Conductance map
 - determine criteria
 - dI/dV at V_{bias}
 - dI/dV at zero volts
 - gap in dI/dV
 - assign to each pixel

Conductivity Map

Measure dI/dV Directly

- modulate bias with small sinusoidal voltage

$$V_{bias} + dv \sin(\omega t)$$



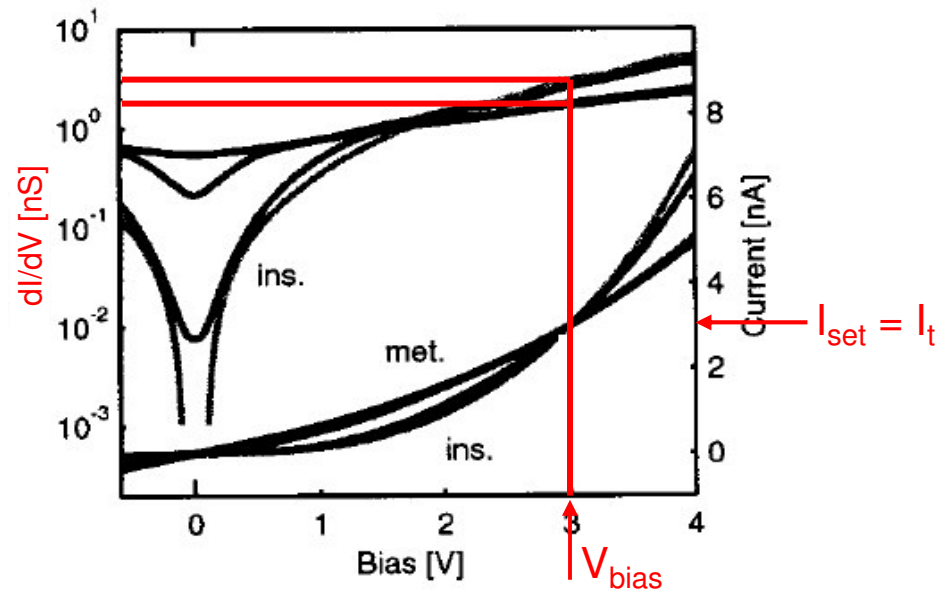
- scan topography

$$\omega \gg BW_{FEEDBACK} \longrightarrow \text{feedback cannot react}$$

- lock-in amplifier measures dI/dV

$$V_{bias} \gg dv \longrightarrow \text{measure } dI/dV \text{ directly}$$

- with each pixel, record both topography and lock-in output



“Standard” Lock-In Technique

- bias modulated with small sinusoidal voltage

$$V_{bias} + dv \sin(\omega t) \rightarrow I_t = f(V_{bias} + dv \sin(\omega t))$$

- for small dv , tunneling current, I_t , can be approximated,

Taylor Series

$$I_t(V_{bias} + dv \sin(\omega t)) \approx I(V_{bias}) + \left. \frac{dI}{dV} \right|_{V_{bias}} dv \sin(\omega t)$$

- IV converter measures tunneling current

$$V_{IV} = A_{IV} I_t(V_{bias} + dv \sin(\omega t)), \quad A_{IV} \approx 1V/nA$$

- lock-in shifts reference signal phase

$$V_L \sin(\omega_L t + \theta)$$

- lock-in PSD multiplies V_{IV} and V_L

$$V_{psd} = V_{IV} V_L \sin(\omega_L t + \theta) = \left[A_{IV} I(V_{bias}) + A_{IV} \left. \frac{dI}{dV} \right|_{V_{bias}} dv \sin(\omega t) \right] V_L \sin(\omega_L t + \theta)$$

$$= A_{IV} I(V_{bias}) V_L \sin(\omega_L t + \theta) + \frac{1}{2} A_{IV} \left. \frac{dI}{dV} \right|_{V_{bias}} dv V_L \cos[(\omega - \omega_L)t - \theta] - \frac{1}{2} A_{IV} \left. \frac{dI}{dV} \right|_{V_{bias}} dv V_L \cos[(\omega + \omega_L)t + \theta]$$

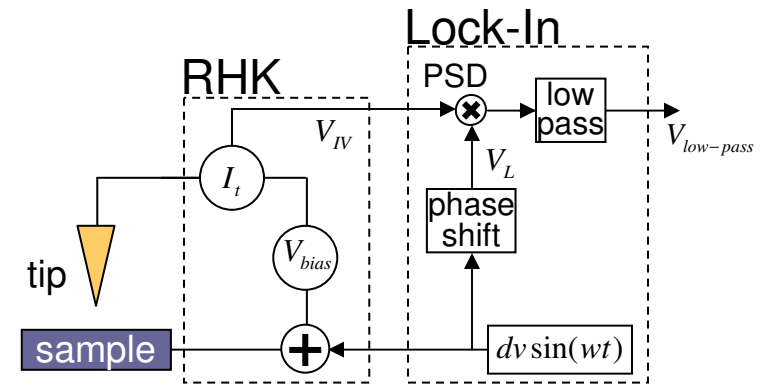
- for $\omega = \omega_L$,

$$V_{psd} = A_{IV} I(V_{bias}) V_L \sin(\omega_L t + \theta) + \frac{1}{2} A_{IV} \left. \frac{dI}{dV} \right|_{V_{bias}} dv V_L \cos[\theta] - \frac{1}{2} A_{IV} \left. \frac{dI}{dV} \right|_{V_{bias}} dv V_L \cos[2\omega_L t + \theta]$$

- lock-in low-pass filter eliminates all ac components

$$V_{low-pass} = \frac{1}{2} A_{IV} \left. \frac{dI}{dV} \right|_{V_{bias}} dv V_L \cos[\theta] \xrightarrow{\text{DualPhase}} \frac{1}{2} A_{IV} \left. \frac{dI}{dV} \right|_{V_{bias}} dv V_L$$

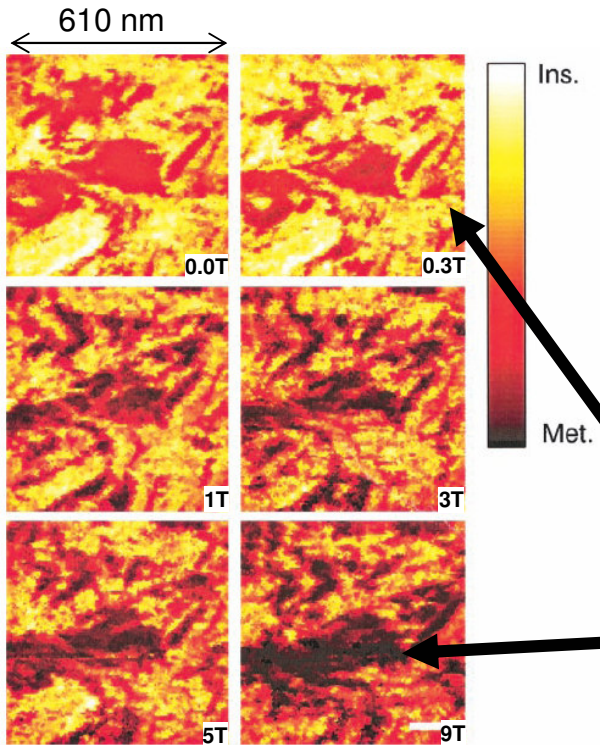
→ $\omega_{NOISE} \neq \omega$ rejected



← slope

Earlier Results: Matthias

STS in Applied Magnetic Field

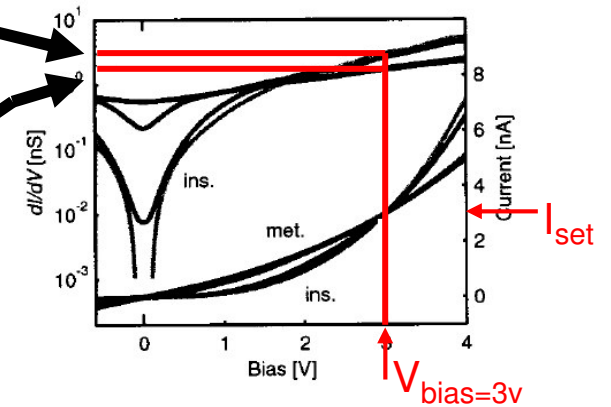


Material

- $\text{La}_{0.7}\text{Ca}_{0.3}\text{MnO}_3$ (10-100 nm) on SrTiO_3
- $\text{YBa}_2\text{Cu}_3\text{O}_y$ template for low-resistant contact
- STO \rightarrow tensile strain

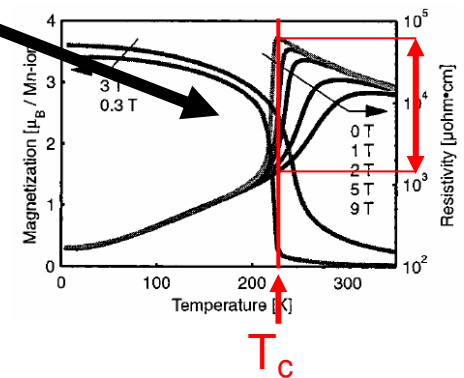
Method

- conductance map with lock-in, $V_{\text{bias}}=3\text{V}$
- light = insulating
- dark = metallic
- just below T_c to maximize CMR
- measured in PPMS



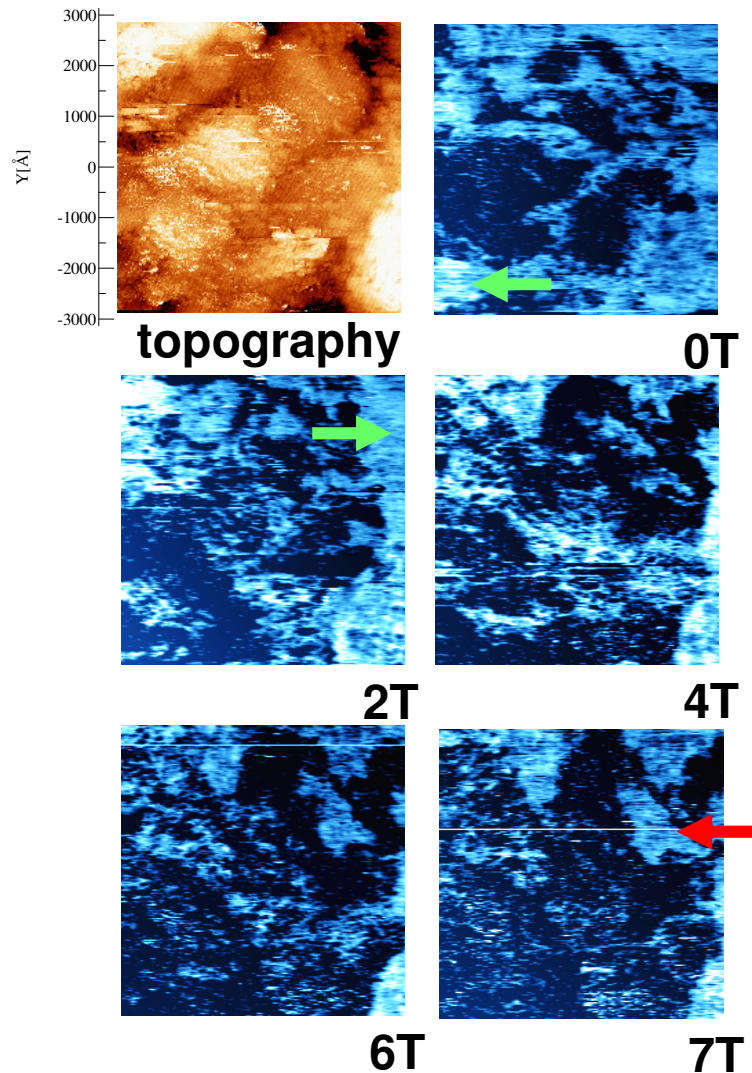
Observations

- increase applied magnetic field \rightarrow more dark area
 - \rightarrow insulating regions to metallic
 - \rightarrow metallic percolation paths
 - \rightarrow reduction in macroscopic resistivity
 - \leftrightarrow CMR



Recent Results

STS in Applied Magnetic Field



$V_{\text{bias}} = 2.0\text{v}$, $I_{\text{set}} = 200\text{pA}$; $A_{\text{lock-in}} = 24\text{mv}$, $f = 1.9\text{kHz}$

Material

- $\text{La}_{0.7}\text{Ca}_{0.3}\text{MnO}_3$ (100 nm) on Nb-doped SrTiO_3
→ strained (~tensile 0.6%)
- Nd doped enhance STO conduction
- sample L407

Method

- conductance map with lock-in, $V_{\text{bias}}=2\text{v}$ no tunneling $V < 2.0\text{v}$
- light = insulating
- dark = metallic
- $T=50\text{K}$
- measured in He gas

Observations

- similar to Matthias
- limited correlation to topography ← not topo or defect
- increased AMF → increased metallic area (← green)
- some increase of insulating area (← red)
- **reversible? reproducible?**

Other Results: Becker *et al.*

STS with Varied Temperature

Material

- $\text{La}_{0.7}\text{Sr}_{0.3}\text{MnO}_3$ (50 nm) on MgO \rightarrow epitaxial
 \rightarrow strained (\sim compressive 8%)

Method

• full I-V

- I-V sweep $\pm 0.6\text{V}$ with $V_{\text{bias}}=2\text{V}$
- every 5th pixel
- fit 5th-order polynomial
- slope at $V = 0.0$
- spatially smoothed

• insulating/metallic threshold criteria

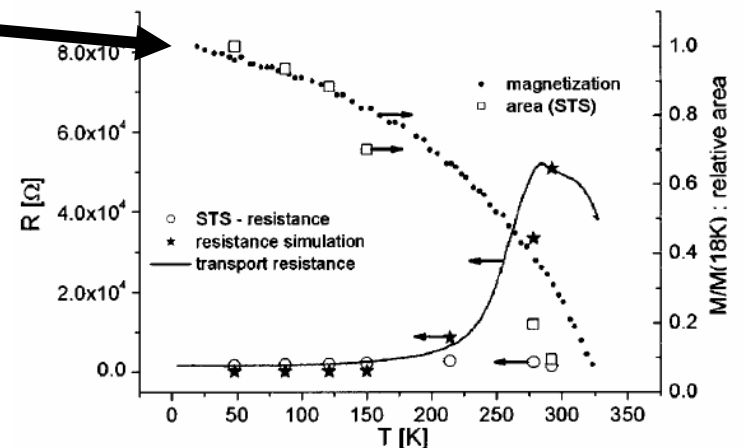
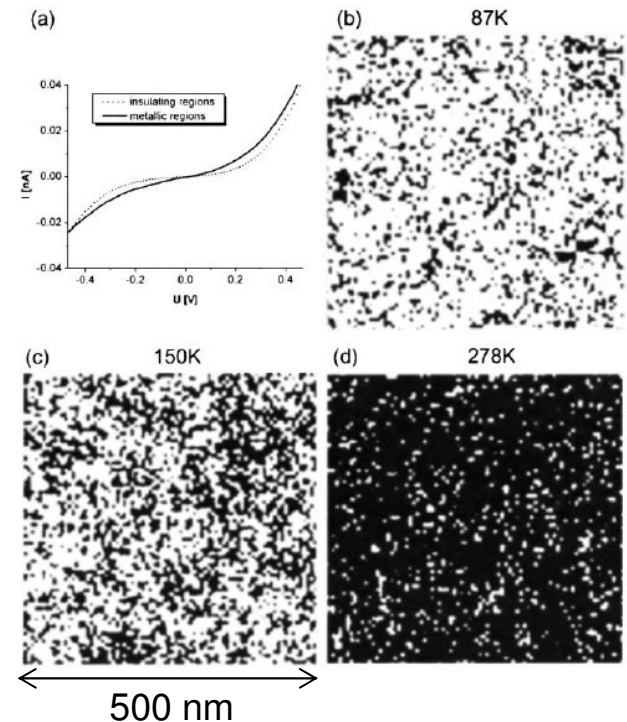
- $dI/dV < 5.9\text{e-}3 \text{ nA/V} \rightarrow$ insulating \rightarrow black
- $dI/dV > 5.9\text{e-}3 \text{ nA/V} \rightarrow$ metallic \rightarrow white
- magnetization : metallic domain area

• measured in UHV with cut Pt-Ir tip, rapid cool to 50K

to avoid
oxygen loss

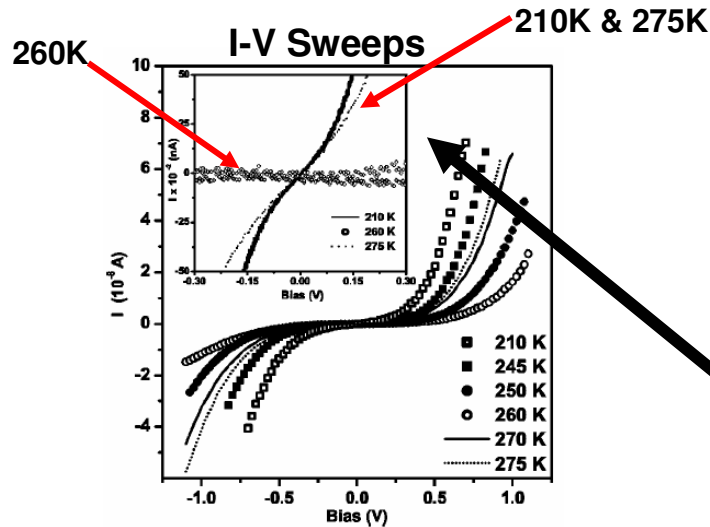
Observations

- claim correspondence between area and magnetization
- metallic region mean tunneling conductance does not explain R-T peak (\circ)
- but resistor network simulations demonstrate R-T peak ($*$)
- **inhomogeneities** \rightarrow MIT



Other Results: Mitra *et al.*

STS with Varied Temperature



Material

- $\text{La}_{0.7}\text{Ca}_{0.3}\text{MnO}_3$ (50 nm) on NdGaO_3
- LCMO epitaxial and strain free on NGO

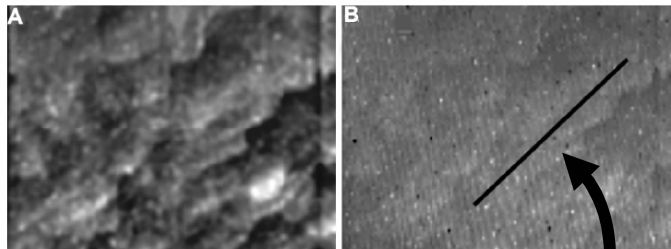
Method

- I-V (not conductance map)
- lock-in conductance map with $V_{\text{bias}}=100\text{mV}$
- measured in HV with Pt-Ir tip

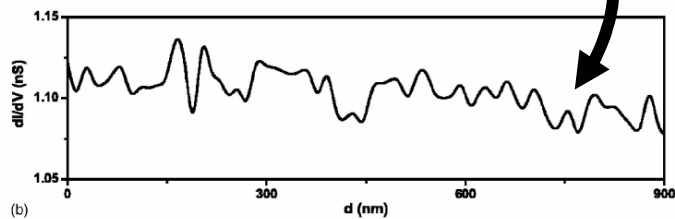
Observations

- strong suppression of tunneling current at $T_c = 268\text{K}$
- strain free \rightarrow no electronic phase separation $T=265\text{K}$
- topography with step (0.4 nm) & terrace structure
- sharp MIT & low residual resistivity \rightarrow “quality film”
- **R-T peak explained by changes to DOS**

Topography

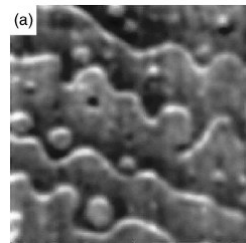


Conductance Map



Matthis

PS on LCMO single crystal
broad R-T peak on 15 nm film

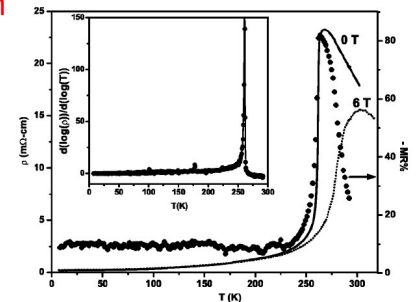


1.2 μm

$T = 300\text{K} \ \& \ 100\text{K}$

$V_{\text{bias}} = 100\text{mV}$

$I_t = 0.5 \text{ nA}$



Other Methods: Conducting AFM

C-AFM → measure topography & spectroscopy independently

- contact AFM for topography
- apply V_{bias} to conducting tip
- measure current

Problems

- tip wear removes conductive coating
- commercially available conductive tips use laser to measure deflection → remote alignment difficult

Solutions

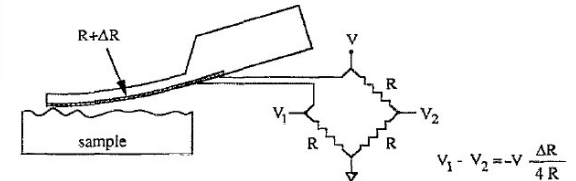
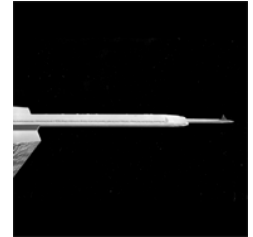
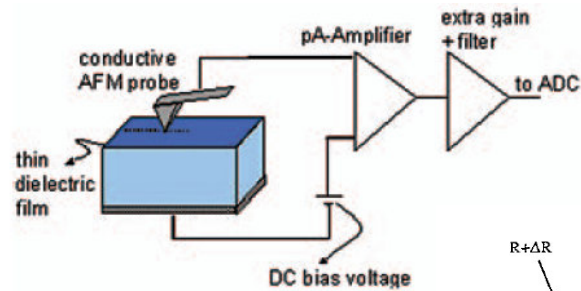
- use conductive diamond tip coating
- modify commercial piezoelectric & piezoresistive tips

- piezoresistive → contact AFM → I-V

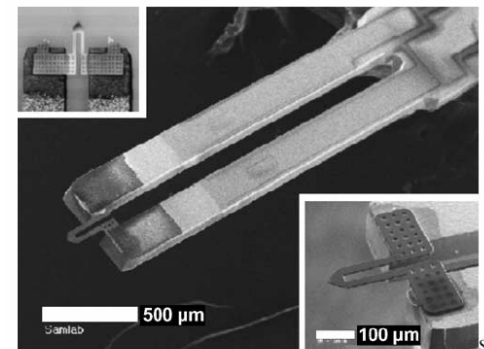
- piezoelectric → non-contact AFM → $\langle I_t(z, A) \rangle \approx \frac{I_t(z, 0)}{\sqrt{4\pi\kappa_t A}}$

dynamic → changes in strain

- make conductive AFM with quartz tuning fork (piezoelectric)



Piezoresistive (Tortonese *et al.*)
Available from Veeco




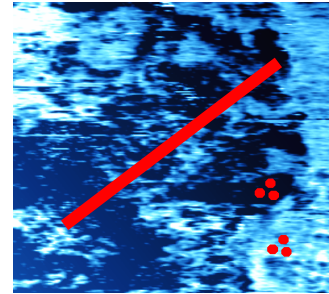
Piezoelectric (Akiyama *et al.*)
Available (?) from NanoWorld

Next Steps

STM

- Immediate

- further investigate tip etching *etched tungsten, Pt-Ir*
- reproduce results with varied Temp & AMF
- measure full I-V (every pixel, along line or selected spots) 
- miscut substrate (STO or NGO or ?) *what will show step-edge induced strain*



- Medium-Term

- improvements to STM → vibration isolation, “residual” 50Hz
- atomic resolution

AFM

- Immediate

- investigate (modified) commercial AFM tips
- improvements to our AFM

- Medium-Term

- conductive AFM at RT with our existing AFM *need current amplifier*

- Longer-Term

- low-temperature AFM